

AMENDMENT TRANSMITTAL LETTER (Large Entity)
 Applicant(s): Katsuji Iguchi, Sheng Teng Hsu, Yoshi Ono and Jer-shen Maa

Docket No.
 SLA0636

Serial No
 10/035,503

Filing Date
 10/25/01

Examiner
 Christopher W. Lattin

Group Art Unit
 2812

Invention: Method of Fabricating Deep Sub-Micron CMOS Source/Drain with MDD and Selective CVD Silicide

TO THE COMMISSIONER FOR PATENTS:

Transmitted herewith is an amendment in the above identified application.

The fee has been calculated and is transmitted as shown below.

CLAIMS AS AMENDED

	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER OF EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	21 -	22 =	0	x \$18.00	\$0.00
INDEP. CLAIMS	4 -	4 =	0	x \$84.00	\$00.00
Multiple Dependent Claims (check if applicable) _____					\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00

- ☒ No additional fee is required for amendment.
- ☐ Please charge Deposit Account No. 19-1457 in the amount of _____
 A duplicate copy of this sheet is enclosed.
- ☐ A check in the amount of _____ to cover the filing fee is enclosed.
- ☒ The Commissioner is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account No. 19-1457.
 A duplicate copy of this sheet is enclosed.
- ☒ Any additional fees required under 37 C.F.R. 1.16.
- ☒ Any patent application processing fees under 37 C.F.R. 1.17.

David C. Ripma, Reg. No. 27,672

Dated: MAY 22, 2003

I hereby certify that this correspondence is being facsimile transmitted to the United States Patent and Trademark Office under 37 C.F.R. §1.8 at Fax No. (703) 872-9318 on May 22, 2003.

David C. Ripma, Reg. No. 27,672

Note: Each paper must have its own certificate or transmission, or this certificate must identify each submitted paper. The papers submitted include:

- ☒ This Amendment Transmittal Letter (Duplicate Attached) 2 page(s)
- ☒ Response under 37 CFR § 1.111 11 page(s)
- ☐ Attachments _____ page(s)
- ☐ Petition for Extension of Time under 37 C.F.R. § 1.136 (Duplicate Attached) _____ page

Total pages, including this Transmittal: 13

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Attorney Docket: SLA.0636

Katsuji Iguchi *et al.*

May 22, 2003

Serial No.: 10/035,503

Group #: 2812

Filed: October 25, 2001

Examiner: Christopher W. Lattin

For: METHOD OF FABRICATING DEEP SUB-MICRON CMOS SOURCE/DRAIN
WITH MDD AND SELECTIVE CVD SILICIDE

MS Non-Fee Response
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

RESPONSE TO OFFICE ACTION UNDER 37 C.F.R. § 1.111
Introductory Comments

In the Office Action dated March 6, 2003, the Examiner rejected claims 1, 6, 11, 15, 17 and 21 under 35 U.S.C. § 102(b) as being anticipated by U. S. Patent No. 4,703,551 to Szu Luk *et al.* claims 11, 16, 17 and 22 were rejected under 35 U.S.C. § 102(b) as being anticipated by U. S. Patent No. 5,757,045 to Tsai *et al.* Claims 2-4, 7-9, 12-14 and 18-20 were rejected under 35 U.S.C. § 103(a) as being unpatentable over '551 in view of U. S. Patent No. 6,069,044 to Wu. Claims 5 and 10 were rejected under 35 U.S.C. § 103(a) as being unpatentable over '551 in view of '045. Claim 6 was objected to under 37 C.F.R. § 1.75 as being a substantial duplicate of claim 1.

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RESPONSE TO OFFICE ACTION UNDER 37 C.F.R. § 1.111 for Serial No.
10/035,503